

### IN THE SPECIFICATION

Please amend the abstract at page 13 as follows:

An electro-statically actuated switch having a reduced gap distance between electrodes for reducing actuation voltage is provided. The invention provides more reliable electro-statically actuated switches. ~~The present invention relates to~~ The invention provides a micro-electro-mechanical system (MEMS). ~~The present invention further relates to that includes a recessed, movable electrode. The invention provides electro-statically actuated switches that reduce the likelihood of stiction and beam deformation and that allows lower actuation voltage for electrostatically actuated structures (i.e., switches or mirrors).~~ such as switches and mirrors. The present invention further relates to a A method for fabricating such a design is provided that allows lower actuation voltage.